



FTW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Naoto NAKAMURA et al.

Group Art Unit: 2893

Application No.: 10/528,069

Examiner: H. TRINH

Filed: July 10, 2005

Docket No.: 122733

For: THERMAL TREATMENT APPARATUS, METHOD FOR MANUFACTURING  
SEMICONDUCTOR DEVICE, AND METHOD FOR MANUFACTURING SUBSTRATE

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

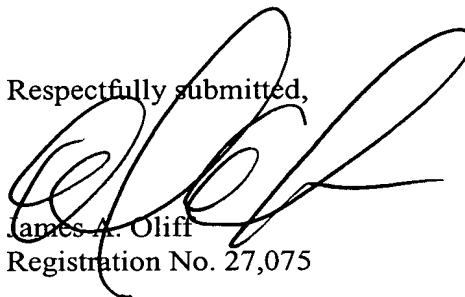
Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed more than three months after the U.S. filing date AND after the mailing date of the first Office Action on the merits, but before the mailing date of a Final Rejection, Notice of Allowance or other action that closes prosecution (e.g., Quayle Action).
- ☒ a. I hereby certify that each item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement. 37 CFR §1.97(e)(1).
- ☒ 2. One or more reference cited herein was cited in a counterpart foreign application. An English language version of the foreign Office Action is attached for the Examiner's information. See References 1 & 2.
- ☒ 3. Also attached for the Examiner's information is an English language version of the February 21, 2008 foreign Office Action from a counterpart foreign application.

- ☒ 4. Japanese Application Publication No. JP-A-2001-358086 cited in the April 8, 2009 Foreign Office Action was previously submitted in an Information Disclosure Statement filed March 15, 2005.
- ☒ 5. Japanese Application Publication Nos. JP-A-11-340155, JP-A-10-242067, JP-A-2002-231726, JP-A-2001-358086 and JP-A-07-161654 cited in the February 21, 2008 Foreign Office Action were previously submitted in an Information Disclosure Statement filed March 15, 2009.

Respectfully submitted,



James A. Oliff

Registration No. 27,075

Daniel A. Tanner, III  
Registration No. 54,734

JAO:DAT/add

Date: June 12, 2009

**OLIFF & BERRIDGE, PLC**  
**P.O. Box 320850**  
**Alexandria, Virginia 22320-4850**  
**Telephone: (703) 836-6400**

DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461
--